



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Kiyoshi MOTEKI & Satoru OSHIKAWA** : Group Art Unit: **2851**
: :
Application No.: **09/856,384** : Examiner: **Kim, Peter**
: :
Filing Date: **May 21, 2001** : Attorney Docket No.: **25,096 USA**
: :
For: **Optical Apparatus, Exposure Apparatus, Laser Light Source, Gas Supply Method, Exposure Method, and Device Manufacturing Method** :

CERTIFICATE OF MAILING

I hereby certify that this correspondence, along with any papers indicated as being enclosed, are being deposited as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on Friday, February 27, 2004.


Patricia M. Frisoli

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Response To Office Action of August 27, 2003

Sir:

This is in response to the Office Action dated August 27, 2003. A request for a three-month extension of time to respond is included. Please amend the above-identified application as follows:

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 13 of this paper.